



PATENT

In re Application of: Oh et al.

Group Art Unit: 1753

Serial No.: 10/615,842

Examiner: Phasge, Arun S.

Filed: July 10, 2003

Docket No.: 421/170/8/2 CIP

Confirmation No.: 9995

For: DEPOSITION METHOD FOR NANOSTRUCTURE MATERIALS

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AMENDMENT B

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is responsive to the Final Official Action dated September 10, 2007, for which a shortened statutory period for reply extends up to and includes December 10, 2007. Favorable consideration is respectfully requested in view of the following Amendments and Remarks.